

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Eric Bornstein
Application Serial No.: 10/649,910
Filing Date: 08/26/2003
Title: NEAR INFRARED MICROBIAL ELIMINATION LASER
SYSTEM
Examiner: Shay, David M.
Art Unit: 3735
Atty. Docket No.: 093991-0019
Confirmation No.: 5770

SUBMITTED VIA EFS-WEB

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AND REPLY

This paper is in response to the Office Action dated 01/23/2009 for the above-identified application. The Applicant appreciates the Examiner's thorough examination of the subject application, and requests reconsideration and further examination be in light of the following amendments and arguments.

Please amend the application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper; and

Remarks begin on page 4 of this paper.